

### REMARKS

This application has been reviewed in light of the "Final" Office Action dated November 5, 2003. Claims 1-30 remain pending in this application. Claim 1 is the sole independent claim. Claim 1 has been amended to even further clarify the claimed subject matter.

In the Office Action, Claims 1-30 were rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent No. 6,017,259 (Motoi et al.) in view of U.S. Patent No. 5,564,958 (Itoh et al.).

Applicants strongly believe that Claim 1 as presented immediately prior to this Preliminary Amendment was patentable over the prior art relied on in the Office Action for the reasons given in the Remarks section of the Amendment filed September 11, 2003. Nonetheless, without conceding the propriety of the above rejection, Claim 1 has been amended to further clarify that the disposing step disposes a container on a substrate so as to form a sealed gas-tight atmosphere defined by the container and the substrate, to cover the conductor with the container, except for part of the wiring. It is respectfully submitted that the prior art relied on in the Office Action does not teach or suggest those features. Applicants therefore respectfully request reconsideration of the rejection of Claim 1 in view of the following comments.

The teachings of Motoi et al. were described in sufficient detail in the Remarks section of the Amendment filed September 11, 2003, and the Examiner is respectfully referred to that Remarks section for such description. Suffice it to say that

Motoi et al. discloses in Figure 8, for example, a vacuum processing apparatus comprising a vacuum chamber. A gauging system includes a vacuum chamber 11 and a vacuum pump 12, and an electron-emitting device comprising a substrate 1, a pair of electrodes 2 and 3, an electroconductive film 4, and an electron-emitting region 5, is located within the chamber 11. A power source 13 applies a device voltage  $V_f$  to the device, an ammeter 14 is for metering a device current  $I_f$ , and an anode 15 captures an emission current  $I_e$ .

The Office Action asserts that “Motoi . . . as shown in Figure 8, teaches a vacuum chamber or a container to cover the substrate and the wiring to connect the voltage source to the conductor within the vacuum chamber or container where a voltage is applied to the conductor.” See page 8 of the Office Action, under the heading “***Response to Arguments***”.

Applicants respectfully submit, however, that nothing in Motoi et al. would teach or suggest a step of disposing a container on a substrate so as to form a sealed gas-tight atmosphere defined by the container and the substrate, to cover a conductor with the container, except for part of a wiring, as performed in the context of the method of Claim 1. Accordingly, Claim 1 is deemed to be clearly patentable over Motoi et al.

Itoh et al. is cited in the Office Action for teaching, *inter alia*, operating a heater to increase the temperature within a chamber, evacuation of a display device, introducing a reducing gas, evacuating the reducing gas, and subjecting the display device to evacuation for about six hours. See, e.g., pages 5-6 of the Office Action. However, Itoh

et al. is not seen to teach or suggest anything which would remedy what is missing (i.e., the above-described disposing step) from Motoi et al., as a reference against Claim 1.

For these reasons, even if Motoi et al. and Itoh et al. were to be combined in the manner proposed in the Office Action (assuming such a combination would even be permissible), the resulting combination also would not teach or suggest the above-described disposing step of Claim 1. Accordingly, Claim 1 is deemed clearly patentable over those references, whether considered separately or in combination.

A review of the other art of record has failed to reveal anything that, in Applicants' opinion, would remedy the deficiencies of the art discussed above, as applied against independent Claim 1 herein. Therefore, Claim 1 is respectfully submitted to be patentable over the art of record.

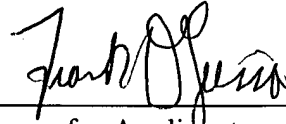
The other rejected claims in this application depend from Claim 1 discussed above, and, therefore, are submitted to be patentable for at least the same reasons as is Claim 1. Since each dependent claim is also deemed to define an additional aspect of the invention, however, individual reconsideration of the patentability of each claim on its own merits is respectfully requested.

In view of the foregoing amendments and remarks, Applicants respectfully request favorable reconsideration and the allowance of the present application.

Applicants' attorney of record may be reached in our New York office by

telephone at (212) 218-2100. All correspondence should continue to be directed to our  
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Respectfully submitted,



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